

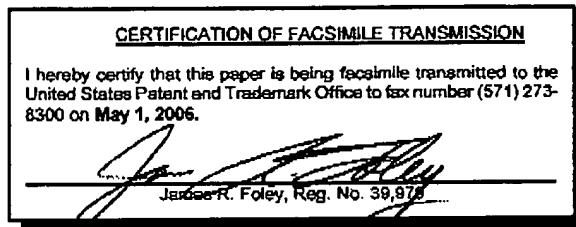
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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No.: 10/800,219 )  
)  
Filed: March 12, 2004 )  
)  
Title: METHOD FOR VERIFYING RET )  
LATENT IMAGE SENSITIVITY )  
TO MASK MANUFACTURING )  
ERRORS )  
)  
Inventors: Nadya G. Strelkova et al. )  
)  
Art Unit: 2825 )  
)  
Examiner: Nelson C. Lam )  
)  
Atty. Ref: 02-2396 )



**RESPONSE TO THE OFFICE ACTION MAILED DECEMBER 1, 2005**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In the matter of the above-identified application and in response to the Office Action mailed December 1, 2005, kindly enter the following amendments and consider the following remarks toward reconsideration of the present application. A Petition for Extension of Time is enclosed, extending the deadline for responding to the Office Action to May 1, 2006. Therefore, this Response is considered timely.

**Amendments to the Title:**

Please change the title to the following:

"Method and Apparatus for Verifying the Post-Optical Proximity Corrected Mask Wafer Image  
Sensitivity to Reticle Manufacturing Errors".

Serial No. 10/800,219

Art Unit: 2825

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